Additions and Corrections

2007, Volume 19

Sean H. Wong, Michael Thiel, Peter Brodersen, Dieter Fenske, Geoffrey A. Ozin, Martin Wegener, and Georg von Freymann*: Highly Selective Wet Etch for High-Resolution Three-Dimensional Nanostructures in Arsenic Sulfide All-Inorganic Photoresist.

Please note the following correction to this article (*Chem. Mater.* **2007**, *19*, 4213–4221): There is an error in the name of a chemical that was provided in the Experimental Section of the manuscript.

In the third paragraph of the Experimental Section, the line containing the error currently reads as follows.

The above reaction procedure was followed using *4-methoxybenzaldehyde* (4.75 mL, 35 mmol) and 1-pyrenecarboxaldehyde (8.06 g, 35 mmol) dissolved in 250 mL of dry benzene and refluxed overnight in a...

The correct description should read as follows.

The above reaction procedure was followed using *4-methoxybenzylamine* (4.75 mL, 35 mmol) and 1-pyrenecarboxaldehyde (8.06 g, 35 mmol) dissolved in 250 mL of dry benzene and refluxed overnight in a...

This correction is essential as it affects the ability for the amine compound that is elaborated upon in the manuscript to be synthesized. We sincerely apologize for this oversight.

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Yanguang Li, Bing Tan, and Yiying Wu*: Ammonia-Evaporation-Induced Synthetic Method for Metal (Cu, Zn, Cd, Ni) Hydroxide/Oxide Nanostructures.

Please note the following addition to this article (*Chem. Mater.* **2008**, *20*, 567−576).

We inadvertently missed citing a reference that describes the synthesis of metal oxide and hydroxide nanostructured thin films using vapor-diffusion catalysis (Schwenzer, B.; Roth, K. M.; Gomm, J. R.; Murr, M.; Morse, D. E. *J. Mater. Chem.* **2006**, *16*, 401). Their synthesis method employs gaseous ammonia to slowly induce crystallization of inorganic materials from aqueous metal salt solutions. This process is similar to that reported in our Article. We thank Dr. Morse and Dr. Schwenzer for bringing this to our attention.10.1021/cm800624g

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